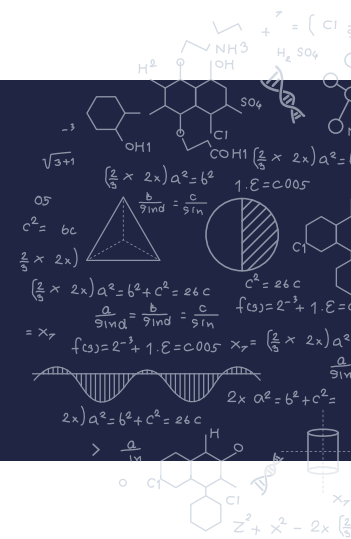


# LICENSING OPPORTUNITY: VOID-FREE METALLIC DIFFRACTION GRATINGS FOR ENHANCED X-RAY INTERFEROMETRY IMAGING



## DESCRIPTION

### Problem

Improvement is needed in X-ray phase contrast imaging systems for better imaging outcomes for soft tissues without the need for radioactive contrast agents.

### Invention

A metallic diffraction grating with recessed features that are optimized for metallic void-free filling by electro-deposition.

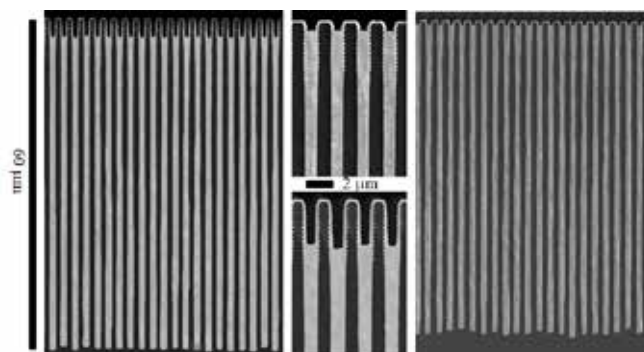
## BENEFITS

### Commercial Application

- X-ray interferometry
- X-ray phase contrast imaging
- X-ray wave-front-sensing
- Optics characterization
- Optics alignment
- Focus characterization at X-ray free-electron lasers (XFELs)
- Biomedicine
- Materials Science
- Security

### Competitive Advantage

- Minimal deposits on the field
- Reduction in post-deposition processing time
- Void-free filled recessed feature with highly uniform filling profiles



Also see patent 10,889,908 and patent application 17/972,816

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